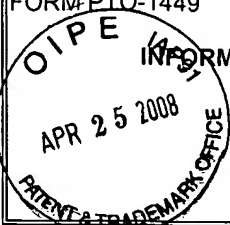


FORM PTO-1449  INFORMATION DISCLOSURE STATEMENT	ATTY. DOCKET 033082 M 343	SERIAL NO. 10/591,476
	APPLICANT: Yasuhiko KOJIMA	
	FILING DATE September 1, 2006	GROUP ART UNIT 1751

U.S. PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE, IF APPROPRIATE
	AA	3,198,167	August 3, 1965	R. Bakish et al.			
	AB	4,321,073	March 23, 1982	Blair			
	AC						
	AD						
	AE						
	AF						
	AG						

FOREIGN PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
							YES	NO
	AH	2005/058789	6/30/2005	WO				
	AI							
	AJ							
	AK							
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER INFORMATION (Including Author, Title, Date, Pertinent Pages, Etc.)

AQ	Supplementary European Search Report (Application No. EP 04 74 6795)
AR	MOUCHE M-J et al., "Metal-organic chemical vapor deposition of copper.....precursor", THIN SOLID FILMS, ELSEVIER-SEQUOIA S.A. LAUSANNE, CH, vol. 262, 1995, pages 1-6, XP002347082, ISSN: 0040-6090
AS	

EXAMINER:	DATE CONSIDERED:
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.